
Symposium (Oral) | Symposium | Highly reliable metallization technology for long term retention

[15p-304-1~10]Highly reliable metallization technology for long term retention

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[15p-304-4]Ellipsometry for evaluating surface cleanliness

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Detection of defects and contaminations is of crucial importance for realizing high-reliable interconnects. To determine physical nature of defects is also becoming important. In the BEOL technologies, various processes such as CMP are involved and versatile inspection ways are demanded in from basic R&D to manufacturing. Ellipsometry is a technique to detect substances on a surface selectively. In this paper application of ellipsometry to BEOL materials are presented.